



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Shoriki NARITA et al.

Serial No. 10/019,700

Filed January 2, 2002

BUMP FORMING APPARATUS FOR  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, CHARGE REMOVAL METHOD  
FOR CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, CHARGE REMOVING UNIT FOR  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, AND CHARGE APPEARANCE  
SEMICONDUCTOR SUBSTRATE

: **Mail Stop: ISSUE FEE**

: **Confirmation No. 1853**

: [Group Art Unit 2825]

: Examiner Igwe U. Anya]

THE COMMISSIONER IS AUTHORIZED  
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ACCOUNT NO. 23-0975

**SUBMISSION OF REFERENCES**

Commissioner for Patents

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Alexandria, VA 22313-1450

Sir:

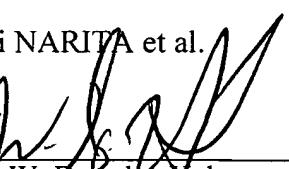
Applicants request that the references listed below be placed in the file of the above-identified application:

USP 6,198,616, 03/2001, Dahimene et al.  
JP 01077111, 03/1989 (Abstract)  
JP 2002009569, 01/2001 (Abstract)  
JP 2002203995, 07/2002 (Abstract)

Respectfully submitted,

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